

**PATENT APPLICATION**

Sheet 1 of 1

<b>FORM PTO-1449</b>  <b>LIST OF PATENTS AND PUBLICATIONS FOR APPLICANT'S INFORMATION DISCLOSURE STATEMENT</b>  (Use several sheets if necessary)	ATTY. DOCKET NO. <b>200312702-1</b>	APPLICATION NO.	CONFIRMATION NO.
APPLICANT <b>Arjang Fartash</b>			
FILING DATE <b>herewith</b>		GROUP	

**REFERENCE DESIGNATION                      U.S. PATENT DOCUMENTS**

EXAMINER INITIAL		DOCUMENT NUMBER	PUBLICATION DATE	NAME	Pages, Columns, Lines Where Relevant Passages or Figures Appear
	1A				
	1B				
	1C				
	1D				
	1E				
	1F				
	1G				
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	1I				
	1J				
	1K				

**FOREIGN PATENT DOCUMENTS**

		DOCUMENT NUMBER	PUBLICATION DATE	NAME OF PATENTEE OR APPLICANT	Pages/Columns/Lines Where Relevant Passages/Figures Appear	Check if Translation attached
	1L					
	1M					
	1N					
	1O					
	1P					

**OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, etc.)**

	1Q	DW Face and DE Prober, J. Vac. Sci. Technol. A, Vol. 5, No. 6, Nov/Dec 1987, "Nucleation of body-centered-cubic tantalum films with a thin niobium underlayer", pp. 3408-3411
	1R	DW Face, ST Ruggiero, and DE Prober, J. Vac. Sci. Technol. A, Vol. 1, No. 2, Apr-June 1983, "Ion beam deposition of Nb and Ta refractory superconducting films", pp. 326-330
	1S	DW Matson, MD Merz, and ED McClanahan, J. Vac. Sci. Technol. A, Vol. 10, No. 4, Jul/Aug 1992, "High rate sputter deposition of wear resistant tantalum coatings", pp. 1791-1796

EXAMINER	DATE CONSIDERED
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